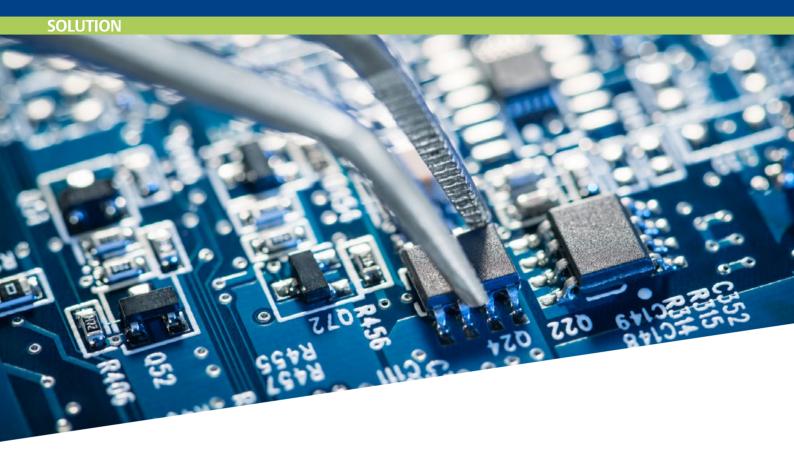
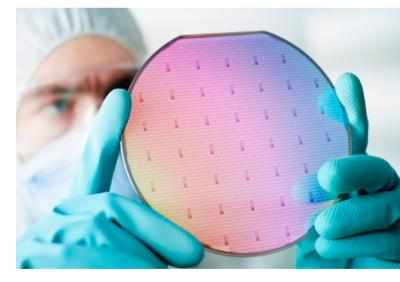
Pressure Control Solutions for Semiconductor Manufacturing Optimize fabrication yield rates with TESCOM™ pressure regulators



Ensure the Purity of Process Gases

- TESCOM pressure regulators maintain and control pressure with accuracy, precision, and stability across a wide range of flows.
- Devices integrate ultra high-purity designs that avoid contamination and prevent wafer and chip failure during the fabrication process.
- Regulators are suitable for a variety of operating conditions including primary and secondary pressure regulation functions for both bulk and specialty gases.



TESCOM[™]



Simple, Lightweight and Hygienic Designs

Ideal for the semiconductor industry, TESCOM pressure regulators are simple and lightweight — featuring high accuracy and high purity, large flow ranges, and minimal internal volumes to reduce media contact points. Our products deliver superior performance in the presence of hazardous media, reduce maintenance and downtime in cleanrooms and other critical applications, and incorporate various design, material and connection options. To prevent wafer and chip failure, our regulators are available with precision electropolishing that complies with SEMI F19 standards. As a global organization, Emerson will help you meet your production needs with both standard and custom solutions, fast delivery, and local support.

Technical Features and Specifications

- Welded fittings include VCR®, IGS or Tube Stub
- Ultra-high inlet pressure: up to 5,300 psig
- Ultra-high outlet pressures: up to 4,000 psig
- Full metal diaphragm seals with standard low leakage rates: 1 x 10-9 atm cc/sec He
- Various body materials available: 316 Stainless Steel, 316L VAR and Hastelloy®
- Regulators include springless, threadless, and singleand dual-stage options
- Flow ranges: 10 standard cubic centimeters per minute (SCCM) to 4,200 standard liters per minute (SLPM)

Application Range	Regulator Series
High-Purity Gas Cabinet Systems	64-2800, 74-2400, 74-3000, 64-3400, 64-5000, and 64-3600 Series
Valve Manifold Boxes	64-2600 and 64-5400 Series
Bulk Specialty Gas Systems	74-3800, 64-3200, 449-254, 44-3200, and 23 Series
Process Equipment Systems	12, M1, M4 stick, and 64-3600 Series Backpressure 44-2300 and 44-4700 Series
Gas Hook-Up	64-2600, 64-5400, SG1, SG,; and 44-3200 Series
Chemical Pressure Control Systems	ER5000 and FM-005 Series













